09/502,534

1/39/4

DIALOG(R) File 345: Inpadoc/Fam. & Legal Stat

(c) 2001 EPO. All rts. reserv.

12950966

Basic Patent (No, Kind, Date): JP 6188294 A2 19940708 <No. of Patents: 005> Patent Family:

Patent No Kind Date Applic No Kind Date A 19930526 JP 6188294 A2 19940708 JP 93124458 (BASIC)

 JP 8068772
 A2 19960312
 JP 95126723
 A 19950525

 US 5578821
 A 19961126
 US 371458
 A 19950111

 US 5665968 19970909 US 607191 A 19960226 19980210 US 606854 A 19960226 A US 5717204 Α

Priority Data (No, Kind, Date):

US 889460 A 19920527

US 252763 A 19940602

US 371458 A 19950111

US 889460 B1 19920527

US 607191 A 19960226

US 252763 B1 19940602

US 889460 B2 19920527

US 606854 A 19960226

PATENT FAMILY:

JAPAN (JP)

Patent (No, Kind, Date): JP 6188294 A2 19940708

EQUIPMENT AND METHOD OF AUTOMATIC SUBSTRATE INSPECTION USING CHARGED PARTICLE BEAM (English)

Patent Assignee: KLA INSTR CORP

DAN MAISUBAAGAA; ARAN DEII BUROODEII; ANIRU EE Author (Inventor): DESAI; DENISU JII EMUGE; TSUON UEI CHIEN; RICHIYAADO SHIMONZU; DEEBU II EE SUMISU; EIPURIRU DATSUTA; JIEI KAAKUUTSUDO EICHI RAFU; RESURII EE HONFUI; HENRII PIASU PAASHI; JIYON MAKUMAATORII; ERITSUKU MANROO

Priority (No, Kind, Date): US 889460 A 19920527 Applic (No, Kind, Date): JP 93124458 A 19930526

IPC: * H01L-021/66; G01R-031/302

Derwent WPI Acc No: * G 95-001507; G 95-001507

Language of Document: Japanese

Patent (No, Kind, Date): JP 8068772 A2 19960312

APPARATUS AND METHOD FOR AUTOMATIC MASK INSPECTION BY USING ELECTRON BEAM MICROSCOPY (English)

Patent Assignee: KLA INSTR CORP

Author (Inventor): DAN MAISUBAAGAA; ARAN DEII BUROODEII; TSUON UEI CHIEN; JIYATSUKU WAI JIYOO; BURAIAN JIEI GURENON

Priority (No, Kind, Date): US 252763 A 19940602

Applic (No, Kind, Date): JP 95126723 A 19950525

IPC: * G01N-023/225; G01M-011/00; G01N-023/203; G21K-005/04; H01J-037/28; H01L-021/66

Derwent WPI Acc No: * C 96-197514; C 96-197514

Language of Document: Japanese

UNITED STATES OF AMERICA (US)

Patent (No, Kind, Date): US 5578821 A 19961126

ELECTRON BEAM INSPECTION SYSTEM AND METHOD Electron beam inspection system and method (English)

Patent Assignee: KLA INSTR CORP (US)

Author (Inventor): MEISBERGER DAN (US); BRODIE ALAN D (US); DESAI ANIL A (US); EMGE DENNIS G (US); CHEN ZHONG-WEI (US); SIMMONS RICHARD (US); SMITH DAVE E A (US); DUTTA APRIL (US); ROUGH J KIRKWOOD H (US); HONFI LESLIE A (US); PEARCE-PERCY HENRY (US);

```
MCMURTRY JOHN (US); MUNRO ERIC (GB)
    Priority (No, Kind, Date): US 371458 A 19950111; US 889460 B1
      19920527
   Applic (No, Kind, Date): US 371458 A 19950111
   National Class: * 250310000; 250311000; 250396000R; 250396000ML;
      250397000
   IPC: * H01J-037/00
   Derwent WPI Acc No: * G 95-001507
   Language of Document: English
  Patent (No, Kind, Date): US 5665968 A 19970909
    INSPECTING OPTICAL MASKS WITH ELECTRON BEAM MICROSCOPY (English)
   Patent Assignee: KLA INSTR CORP (US)
   Author (Inventor): MEISBURGER DAN (US); BRODIE ALAN D (US); CHEN
     ZHONG-WEI (US); JAU JACK Y (US); GRENON BRIAN J (US)
   Priority (No, Kind, Date): US 607191 A 19960226; US 252763 B1
      19940602; US 889460 B2 19920527
   Applic (No, Kind, Date): US 607191 A
                                         19960226
   National Class: * 250310000; 250306000; 250307000
   IPC: * H01J-037/26
   Derwent WPI Acc No: * C 96-197514; G 95-001507
   Language of Document: English
  Patent (No, Kind, Date): US 5717204 A 19980210
    INSPECTING OPTICAL MASKS WITH ELECTRON BEAM MICROSCOPY (English)
   Patent Assignee: KLA INSTR CORP (US)
   Author (Inventor): MEISBURGER DAN (US); BRODIE ALAN D (US); CHEN
     ZHONG-WEI (US); JAU JACK Y (US)
   Priority (No, Kind, Date): US 606854 A 19960226; US 252763 B1
     19940602; US 889460 B2 19920527
   Applic (No, Kind, Date): US 606854 A 19960226
   National Class: * 250310000; 250306000; 250307000; 250397000
   IPC: * H01J-037/26
   Derwent WPI Acc No: * C 96-197514; G 95-001507
   Language of Document: English
UNITED STATES OF AMERICA (US)
 Legal Status (No, Type, Date, Code, Text):
   US 5578821 P
                       19920527 US AA
                                             PRIORITY
                             US 889460 B1 19920527
   US 5578821
                       19950111 US AE
                                             APPLICATION DATA (PATENT)
                             (APPL. DATA (PATENT))
                             US 371458 A 19950111
   US 5578821
                       19950728 US AS02
                                             ASSIGNMENT OF ASSIGNOR'S
                             INTEREST
                             KLA INSTRUMENTS CORPORATION 160 RIO ROBLES
                             STREET SAN JOSE, CALIFORNIA 95161-905;
                            MEISBERGER, DAN: 19950526; BRODIE, ALAN D.:
                             19950607; DESAI, ANIL A.: 19950313; EMGE,
                             DENNIS G.: 19950327; CHEN, ZHO: 19950607;
   US 5578821
                       19961126 US A
                                             PATENT
                       19920527 US AA
                                             PRIORITY
   US 5665968
                            US 889460 B2 19920527
                       19940602 US AA
   US 5665968
                                             PRIORITY
                             US 252763 B1 19940602
                                             APPLICATION DATA (PATENT)
                       19960226 US AE
   US 5665968
                             (APPL. DATA (PATENT))
                             US 607191 A
                                           19960226
                       19970909 US A
   US 5665968
                                             PATENT
                   P
   US 5717204
                       19920527 US AA
                                            PRIORITY
                             US 889460 B2 19920527
   US 5717204
                       19940602 US AA
                                             PRIORITY
```

			US 252763 B1 19940602
US	5717204	P	19960226 US AE APPLICATION DATA (PATENT)
			(APPL. DATA (PATENT))
			US 606854 A 19960226
US	5717204	P	19980210 US A PATENT
US	5717204	P	20000502 US RF REISSUE APPLICATION FILED
			(REISSUE APPL. FILED)
			20000210
US	5717204	P	20000801 US RF REISSUE APPLICATION FILED
			(REISSUE APPL. FILED)
			20000210

Source: All Sources: Area of Law - By Topic: Patent Law: Patents: U.S. Patents: Utility Patents

Terms: patno is 5717204 (Edit Search)

Pat. No. 5717204, *

5,717,204

◆ GET 1st DRAWING SHEET OF 20

Feb. 10, 1998

Inspecting optical masks with electron beam microscopy

REISSUE: Reissue Application filed Feb. 10, 2000 (O.G. Aug. 1, 2000) Ex. Gp.: 2878; Re. S.N. 09/502,534

Reissue Application filed Feb. 10, 2000 (O.G. May 2, 2000) Ex. Gp.: 2878; Re. S.N. 09/502,120

INVENTOR: Meisburger, Dan, San Jose, California Brodie, Alan D., Palo Alto, California Chen, Zhong-Wei, San Jose, California Jau, Jack Y., Fremont, California

ASSIGNEE-AT-ISSUE: KLA Instruments Corporation, San Jose, California (02)

APPL-NO: 606,854

FILED: Feb. 26, 1996

REL-US-DATA:

Continuation of Ser. No. 252,763, Jun. 2, 1994 now abandoned Which is a continuation-in-part of Ser. No. 889,460, May 27, 1992 now abandoned

INT-CL: [6] H01J 37#26

US-CL: 250#310; 250#306; 250#307; 250#397

CL: 250

SEARCH-FLD: 250#310, 306, 307, 492.1, 397

REF-CITED:

U.S. PATENT DOCUMENTS

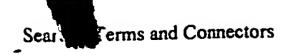
5,502,306 3/1996 * Meisburger et al. 250#310 5,578,821 11/1996 * Meisburger et al. 250#310

PRIM-EXMR: Nguyen, Kiet T.

LEGAL-REP: Jones; Aliston L.

CORE TERMS: electron, mask, substrate, secondary, beam, waveform, detector, inspection, backscatter, electron beam, computer, scan, optical, pixel, phase, quartz, deflection, die, chromium, region, column, lens, alignment, conductive, electrode, layer, energy, memory, processor, correspond

ABST:



• •		• • • • • • • • • • • • • • • • • • • •		•		
exis.com [®]	Practice Pages	Change Clent	Options	Feedback	Sign Off	Help
Search Search Advisor) Get a Document)	Check a Citatio	an)			ECUPSE™	Histor
Sources						
	MANUS COM	aa Orawaa a Ba	stant Car	as from	Endoral (Court
Il Sources: Area of Law - By Topic: Patent Law	v: <u>Multi-Sour</u>	ce Groups : Pa	nem Cas	ses mom	rederar	Jourt
Enter Search Terms			****			
Terms and Connectors						
5,717,204 or 5717204		Searc	:h			
		上豆				
Use connectors to show relation of terms (cat or feline, jane	w/3 doe) <u>more</u>					
Suggest Words and Concepts for Entered	Terms					
Restrict Search Using Document Segment	S					
Optional: Restrict by Date		То				
No Date Restrictions ▼ O From		IU			*	

Search | Search Advisor | Get a Document | Check a Citation

ECLIPSE(TM) | History | Practice Pages | Change Client | Options | Feedback | Sign Off | Help

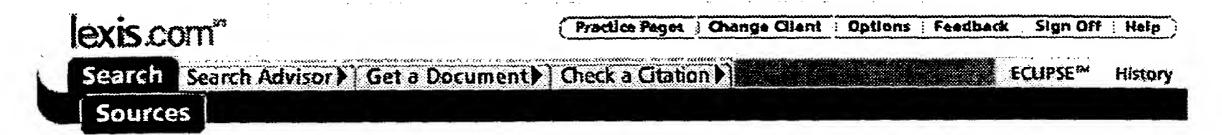
About LEXIS-NEXIS | Terms and Conditions

No documents were found for your search (5,717,204 or 5717204). Please edit your search and try again. You may want to try one or more of the following:

- Check for spelling errors.
- · Remove some search terms.
- Use more common search terms.
- If applicable, look for all dates.

Edit Search

About LEXIS-NEXIS | Terms and Conditions



All Sources: Area of Law - By Topic: Patent Law: Law Reviews & Journals: Intellectual Property Law Review Articles

Enter Search Terms			H 1 7
Terms and Connectors			
5,717,204 or 5717204	Ŀ	Search	
	▼ Jacob mare		
Use connectors to show relation of terms (cat or feling			
Suggest Words and Concepts for Enti-			
Restrict Search Using Document Seg	ments		
Optional: Restrict by Date			
O No Date Restrictions VO From	То		

Search | Search Advisor | Get a Document | Check a Citation

ECLIPSE(TM) | History | Practice Pages | Change Client | Options | Feedback | Sign Off | Help

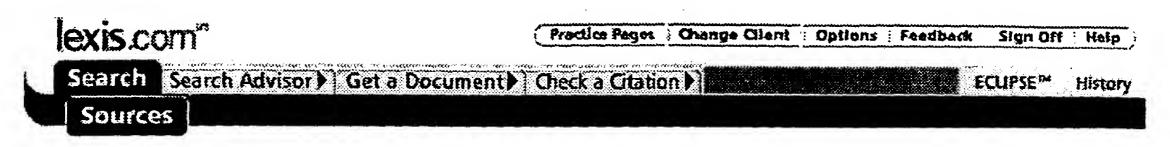
About LEXIS-NEXIS | Terms and Conditions

No documents were found for your search (5,717,204 or 5717204). Please edit your search and try again. You may want to try one or more of the following:

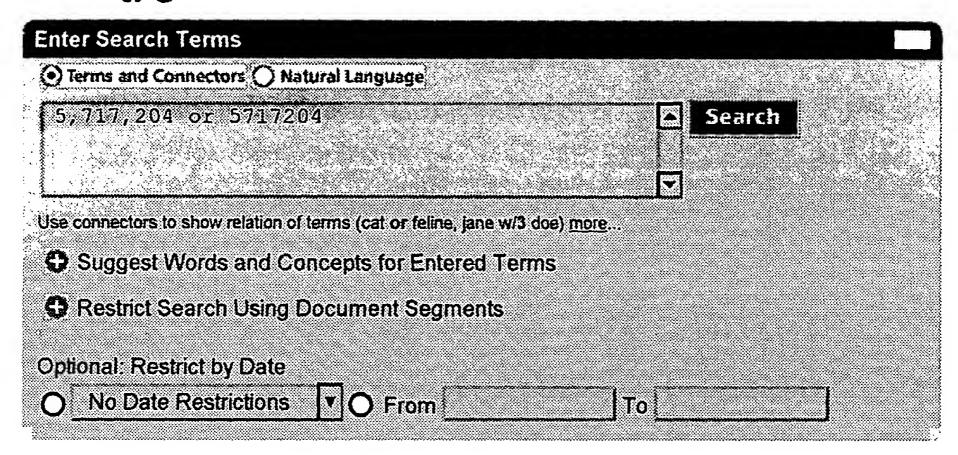
- Check for spelling errors.
- · Remove some search terms.
- Use more common search terms.
- If applicable, look for all dates.

Edit Search

About LEXIS-NEXIS | Terms and Conditions



All Sources: Area of Law - By Topic: Patent Law: Law Reviews & Journals: Harvard Journal of Law & Technology



Search | Search Advisor | Get a Document | Check a Citation

ECLIPSE(TM) | History | Practice Pages | Change Client | Options | Feedback | Sign Off | Help

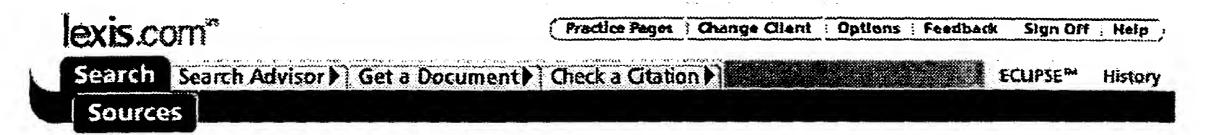
About LEXIS-NEXIS | Terms and Conditions

No documents were found for your search (5,717,204 or 5717204). Please edit your search and try again. You may want to try one or more of the following:

- Check for spelling errors.
- Remove some search terms.
- · Use more common search terms.
- If applicable, look for all dates.

Edit Search

About LEXIS-NEXIS | Terms and Conditions



All Sources: Area of Law - By Topic: Patent Law: Law Reviews & Journals: Journal of Law and Technology

Enter Search Terms			
Terms and Connectors			
5,717,204 or 5717204		Search	
	l T		
Use connectors to show relation of terms (cat or feline, jane w/3 doe) more			
Suggest Words and Concepts for Entered Terms			
Restrict Search Using Document Segments			
Optional: Restrict by Date			
No Date Restrictions ▼ ○ From]To		

Search | Search Advisor | Get a Document | Check a Citation

ECLIPSE(TM) | History | Practice Pages | Change Client | Options | Feedback | Sign Off | Help

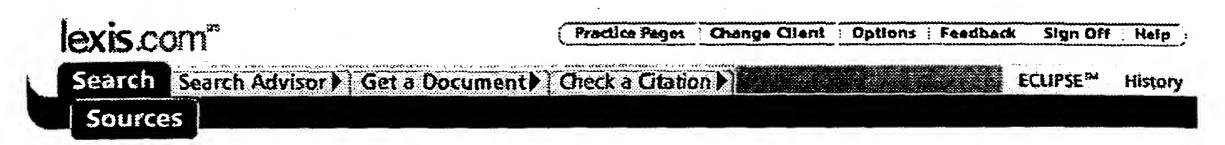
About LEXIS-NEXIS | Terms and Conditions

No documents were found for your search (5,717,204 or 5717204). Please edit your search and try again. You may want to try one or more of the following:

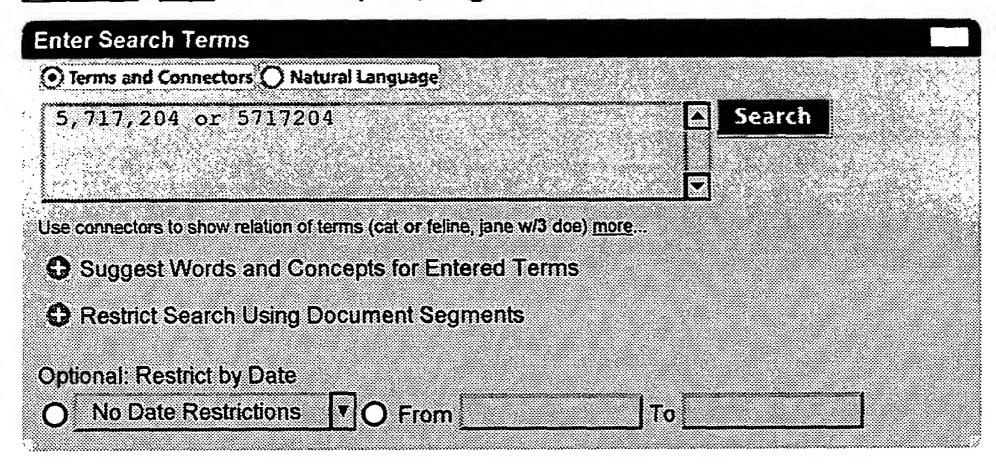
- Check for spelling errors.Remove some search terms.
- · Use more common search terms.
- If applicable, look for all dates.

Edit Search

About LEXIS-NEXIS | Terms and Conditions



All Sources: News: News Group File, All



Search | Search Advisor | Get a Document | Check a Citation

ECLIPSE(TM) | History | Practice Pages | Change Client | Options | Feedback | Sign Off | Help

About LEXIS-NEXIS | Terms and Conditions

No documents were found for your search (5,717,204 or 5717204). Please edit your search and try again. You may want to try one or more of the following:

- Check for spelling errors.
- · Remove some search terms.
- · Use more common search terms.
- If applicable, look for all dates.

Edit Search

About LEXIS-NEXIS | Terms and Conditions

Questel-Orbit:

1/1 LGST - (C) LEGSTAT PN - US 5717204 [US5717204] AP - US 606854/96 19960226 [1996US-0606854] DT - US-P ACT - 19960226 US/AE-A **APPLICATION DATA (PATENT)** {US 606854/96 19960226 [1996US-0606854]} - 19980210 US/A **PATENT** - 20000502 US/RF REISSUE APPLICATION FILED 20000210 - 20000801 US/RF REISSUE APPLICATION FILED 20000210 UP - 2000-31

1/2 PAST - (C) PAST

AN - 200031-001329

PN - 5717204 A [US5717204]

DT - A (UTILITY)

OG - 2000-08-01

CO - REA

ACT - REISSUE APPLICATION FILED

SH - REISSUE APPLICATION FILED

1/1 CRXX - (C) CLAIMS/RRX

AN - 2940859

PN - 5,717,204 A 19980210 [US5717204]

PT - E (Electrical)

PA - Kla Instruments Corp

ACT - 20000210 REISSUE REQUESTED

Issue Date of O.G.: 20000502

Reissue Request Number: 09/502120

Examination Group responsible for Reissue process: 2878

- 20000210 REISSUE REQUESTED

Issue Date of O.G.: 20000801

Reissue Request Number: 09/502534

Examination Group responsible for Reissue process: 2878

UP - 2000-18

UACT- 2000-08-01